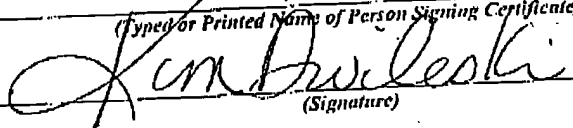


CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8)			Docket No. BU9-99-197
Applicant(s): Furukawa et al.			
Application No. 09/599,783	Filing Date 6/22/2000	Examiner Julio J. Maldonado	Group Art Unit 2823
Invention: METHOD FOR ETCHING A SEMICONDUCTOR SUBSTRATE USING GERMANIUM HARD MASK			

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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application: Furukawa, et al

Serial No.: 09/599,783

Filed: 06/22/2000

Title: Method For Etching A Semiconductor Substrate Using Germanium Hard Mask

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Group Art Unit: 2823

Examiner: Julio J. Maldonado

Docket No.: BU9-99-197

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Sir:

This Request for reconsideration is in response to the Office Action mailed May 17,

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09/599,783

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